

<p>FORM PTO-1449 (Modified)</p> <p><b>OIPE</b></p> <p>INFORMATION DISCLOSURE CITATION IN AN APPLICATION</p> <p>SEP 12 2003 U.S. PATENT AND TRADEMARK OFFICE</p> <p>(Use several sheets if necessary)</p>	<p>Docket No. 378-21-020</p> <p>Applicant James D. Parsons</p> <p>Filing Date 06/27/03</p>	<p>Application Number 10/608,737</p> <p>Group Art Unit</p>
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**U.S. PATENT DOCUMENTS**

## FOREIGN PATENT DOCUMENTS

	Document Number	Date	Country	Class	Subclass	Translation	
						Yes	No

**OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)**

- R. Holands, "Thin-Film Thermocouples on Ceramics", NASA Technical Briefs, March 1997, p. 62: Pt vs PtRh metal thin films are deposited on AlN dies for use as thin-film thermocouples (TCs).
  - Y.H. Chiso et al., "Interfacial Bonding in Brazed and Cofired Aluminum Nitride", ISHM '91 Proceedings, pp. 460-468 (The year of publication is sufficiently earlier than the effective filing date and any foreign priority date.)

**Examiner**

Date Considered

113115

**EXAMINER:** Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.